

MNL 228 201827

SS 1?
FILE JAPIO;J61073071/PN

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COVERS PATENT APPLICATIONS FROM OCT 1976 THRU NOV 1993 (9406)

SS 1 RESULT (1)

SS 2?
PRT FU

-1- (JAPIO)
AN - 86-073071
TI - FLEXIBLE HINGE DEVICE
PA - (2000708) INTERNATL STANDARD ELECTRIC CORP
IN - JIYON, KURISUTOFUAA GURIINUTSUDO; DEIBUIDO, UIRUSON
PN - 86.04.15 J61073071, JP 61-73071
AP - 84.09.14 84JP-191876, 59-191876
IC - G01P-015/125
JC - 46.1 (INSTRUMENTATION--Measurement)

SS 2?
J62207917/PN

SS 2 RESULT (1)

SS 3?
PRT FU

UR1

-1- (JAPIO)
AN - 87-207917
TI - VIBRATION AND ACCELERATION SENSOR
PA - (2000522) FUJITSU LTD
IN - ENDOU, MICHIKO; FUJIWARA, YOSHIAKI; KOJIMA, YUJI
PN - 87.09.12 J62207917, JP 62-207917
AP - 86.03.10 86JP-050531, 61-50531
SO - 88.02.27 SECT. P, SECTION NO. 671; VOL. 12, NO. 66, PG. 142.
IC - G01H-011/06; G01P-015/125
JC - 46.1 (INSTRUMENTATION--Measurement)
AB - PURPOSE: To obtain the titled sensor which can be easily
manufactured by a simple constitution, and also, has a high
sensitivity and a high accuracy, by forming a cantilever which is
bent by receiving an acceleration, to a sandwich structure which
has been inserted and held by a conductive metallic thin film and
an SiO₂ film.

CONSTITUTION: A minute cantilever 11 which has been formed to a sandwich structure by inserting and holding an Al thin film 12 by SiO₂ films 13, 14 is provided on an Si substrate 10, and also, in a position opposed to the cantilever 11 of the Si substrate 10, a high conductive layer 15 is formed by diffusing an impurity. When the cantilever 11 is bent by receiving an acceleration, a variation of an electric capacity is generated between the conductive metallic thin film 12 of the cantilever 11, and the high conductive layer 15 of the Si substrate 10, therefore, by detecting it, a vibration or an acceleration can be sensed. Also, by forming the conductive layer of the cantilever 11 by the metallic thin film 12, the man-hour for manufacture can be curtailed. Moreover, by providing an FET on the same substrate, the vibration and acceleration can be sensed with a high sensitivity and a high accuracy.

SS 3?
FILE WPAT;J61073071/PN

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COVERS 1963 THRU WEEKLY UPDATE 9418/UP, 9418/UPEQ, 9415/UPA, 9408/UPB;
WPI 9417/UPEQ

DERWENT PATENT DRAWINGS NOW AVAILABLE. SEE NEWSDOC N213

TERM (J61073071/PN) NOT FOUND.
SS 1 RESULT (0)

SS 2?
SAVE MNL

SAVE MNL COMPLETED.
SS 2?
BYE

SS 2 RESULT (68)

SS 3?
STOP Y

SESSION FINISHED 06/29/94 2:45 P.M. (CENTRAL TIME)
ELAPSED TIME ON WPAT: 0.01 HRS.
\$2.10 EST COST CONNECT TIME.
\$2.10 EST TOTAL COST THIS WPAT SESSION.

ELAPSED TIME THIS SESSION: 0.06 HRS.
\$8.12 EST COST CONNECT TIME.
\$0.78 EST COST TELECOM.
\$1.30 EST COST ONLINE PRTS: 2
\$9.42 EST TOTAL COST THIS TERMINAL SESSION.